

Response under 37 C.F.R. 1.55
- Expedited Examining Procedure -
Examining Group 1763

BOX AF
Docket 83401RLO

AF
1100

Customer No. 01333

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Steven A. Van Slyke, et al

Group Art Unit: 1763

Examiner: Richard R. Bueker

THERMAL PHYSICAL VAPOR
DEPOSITION SOURCE FOR MAKING
AN ORGANIC LIGHT-EMITTING
DEVICE

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deposited today with the United States Postal
Service as first class mail in an envelope addressed
to Commissioner for Patents, Washington, D.C. 20231.

Paula West

Date

Serial No. US 09/996,415

Filed 28 November 2001

Commissioner for Patents
Washington, D.C. 20231

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TC 1700

Transmitted herewith is an amendment in the above-identified application:

- ☒ No additional fee is required.
☐ The fee has been calculated as shown below:

	(Col. 1)		(Col. 2)	(Col. 3)	OTHER THAN A SMALL ENTITY	
	CLAIMS REMAINING AFTER AMENDMENT		* HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL	18	MINUS	20	0	X 18	\$ 0
INDEP	2	MINUS	3	0	X 84	\$ 0
FIRST PRESENTATION OF MULTIPLE DEPENDENT CLAIM					+ 280	\$ 0
TOTAL						\$ 0

* The "Highest Number Previously Paid For" (Total or Independent) is the highest number found from the equivalent box in Col. 1 of a prior amendment or the number of claims originally filed.

☐ Please charge my Eastman Kodak Company Deposit Account No. 05-0225 in the amount of \$ 0.
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☒ The Commissioner is hereby authorized to charge payment of
the following fees associated with this communication or credit any overpayment to Eastman Kodak
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☒ Any additional filing fees required under 37 CFR 1.16.

☒ Any patent application processing fees under 37 CFR 1.17.
(For Extensions of Time and other Petitions to the Assistant Commissioner)

Raymond L. Owens/phw
Telephone: (585) 477-4653
Facsimile: (585) 477-4646

Attorney for Applicants
Registration No. 22,363



Response under 37 C.F.R. 1.116
- Expedited Examining Procedure -
Examining Group 1763

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Steven A. Van Slyke, et al

THERMAL PHYSICAL VAPOR
DEPOSITION SOURCE FOR
MAKING AN ORGANIC LIGHT-
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5 Commissioner for Patents
Washington, D.C. 20231

Sir:

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RESPONSE UNDER 37 CFR 1.116

In response to the Office Action mailed July 8, 2002, please amend
the above-identified application as follows, without prejudice.

In the Claims:

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Please amend Claim 1 as set forth below:

1. (once amended) A thermal physical vapor deposition
source for vaporizing solid organic materials and applying a vaporized organic
material as a layer onto a surface of a structure in a chamber at reduced pressure in
forming an organic light-emitting device (OLED), comprising:

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- a) a bias heater defined by side walls and a bottom wall, the
side walls having a height dimension H_B ;
- b) an electrically insulative container disposed in the bias
heater, the container receiving solid organic material which can be vaporized, the
container defined by side walls and a bottom wall, and the container side walls